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Respectfully submitted,



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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet 1

of 1

Application Number

10/036,321

Filing Date

December 26, 2001

First Named Inventor

Stevens, et al.

Group Art Unit

1734

Examiner Name

Laura E. Edwards

Attorney Docket Number

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Submission Date

June 1, 2004

NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
	C1	Verteq Online Products Overview, www.verteq.com	
	C2	Censak, R.J., et al., "Spin Basket," IBM Technical Disclosure Bulletin, Vol. 18, No. 8, pp. 2476-77, 1/1976	
	C3	Singer, P., "Wafer Processing," Semiconductor International, "Non-Uniformity of Copper Electroplating Studied", p. 70, 6/1998	
	C4	Colombo, L., "Wafer Back Surface Film Removal," Spin Etch Technology, Central R&D, SGS-Thomson Microelectronics, Agrate, Italy, 6 pp.	
	C5	©Semitool Inc., "Metallization & Interconnect," 1998, 4 pp.	
	C6	Laurell Technologies Corporation, "Two Control Configurations Available – see WS-400 or WS-400-Lite," 10/19/1998, 6 pp.	
	C7	Singer, P., "Tantalum, Copper and Damascene: The Future of Interconnects," Semiconductor International, June 1998, Pages cover, 91-92, 94, 96 & 98	

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